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Deposition of Nanoparticles Formed in Sih4 Discharges -- Diagnostics and Modeling of Sih4 /H2 Plasmas for the Deposition of Microcrystalline Silicon: the Case of Dual-Frequency Sources -- Introduction To Diamond-Like Carbons -- Diamond-Like Carbon for Applications -- Applications of Dlcs To Bioprocessing -- Plasma Processing of Nanocrystalline Semiconductive Cubic Boron Nitride Thin Films -- Fundamentals on Tribology of Plasma-Deposited Diamond-Like Carbon Films -- Diamond-Like Carbon Thin Films Grown in Pulsed-Dc Plasmas -- Plasma Deposition of N-Tio2 Thin Films -- Investigation of Dlc and Multilayer Coatings Hydrophobic Character for Biomedical Applications -- Creation of Novel Electromagnetic and Reactive Media From Microplasmas -- Nanoblock Assembly Using Pulse Rf Discharges With Amplitude Modulation -- Thomson Scattering Diagnostics of Discharge Plasmas -- Crystallized Nanodust Particles Growth in Low-Pressure Cold Plasmas -- Collection and Removal of Fine Particles in Plasma Chambers.